



AZ[®] 10XT Photoresist

Thick Positive Novolak Photoresist For Plating and Etch Applications

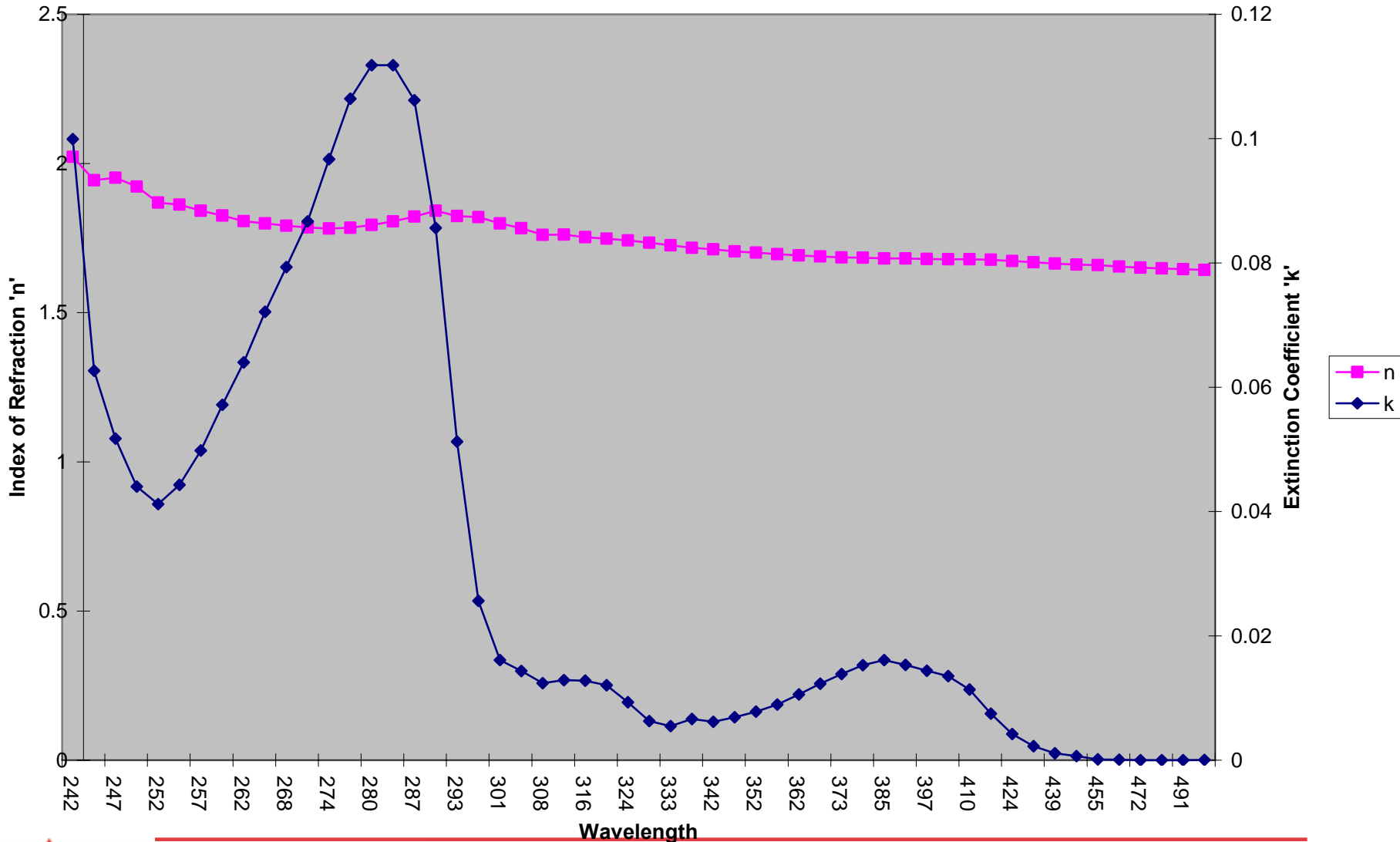
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AZ[®] 10XT Photoresist

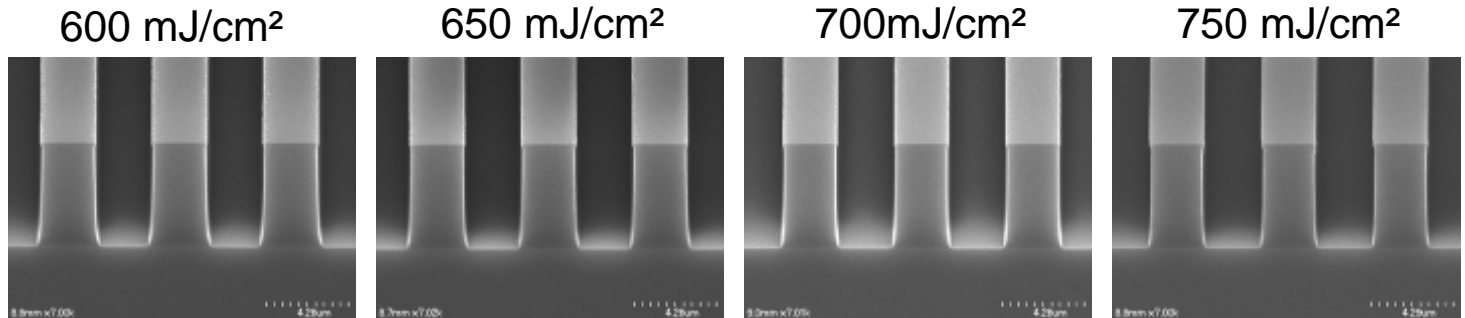
- ▶ AZ[®] 10XT positive photoresist is designed for 5 to 25 micron film thickness in high performance rerouting processes and other plating applications.
- ▶ Three viscosities are available to cover a variety of film thicknesses.
- ▶ PFOS free formulation.
- ▶ Excellent coat capability, 3 to 1 aspect ratios, vertical sidewalls.
- ▶ Sensitive to g, h and i-line wavelengths
- ▶ Compatible with both inorganic and organic developers. Shorter develop times can be realized with inorganic developers, however.

AZ[®] 10 XT Photoresist

Optical Constants (n & k)

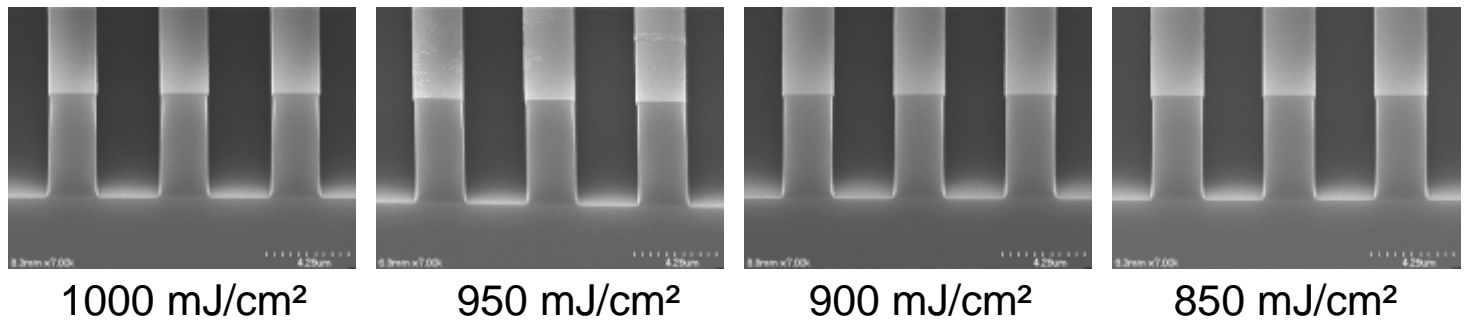
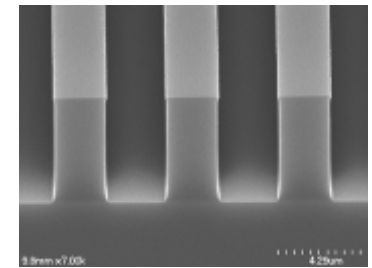


AZ[®] 10XT Photoresist, FT=6 μm 3.0 μm L/S Exposure Latitude on Silicon



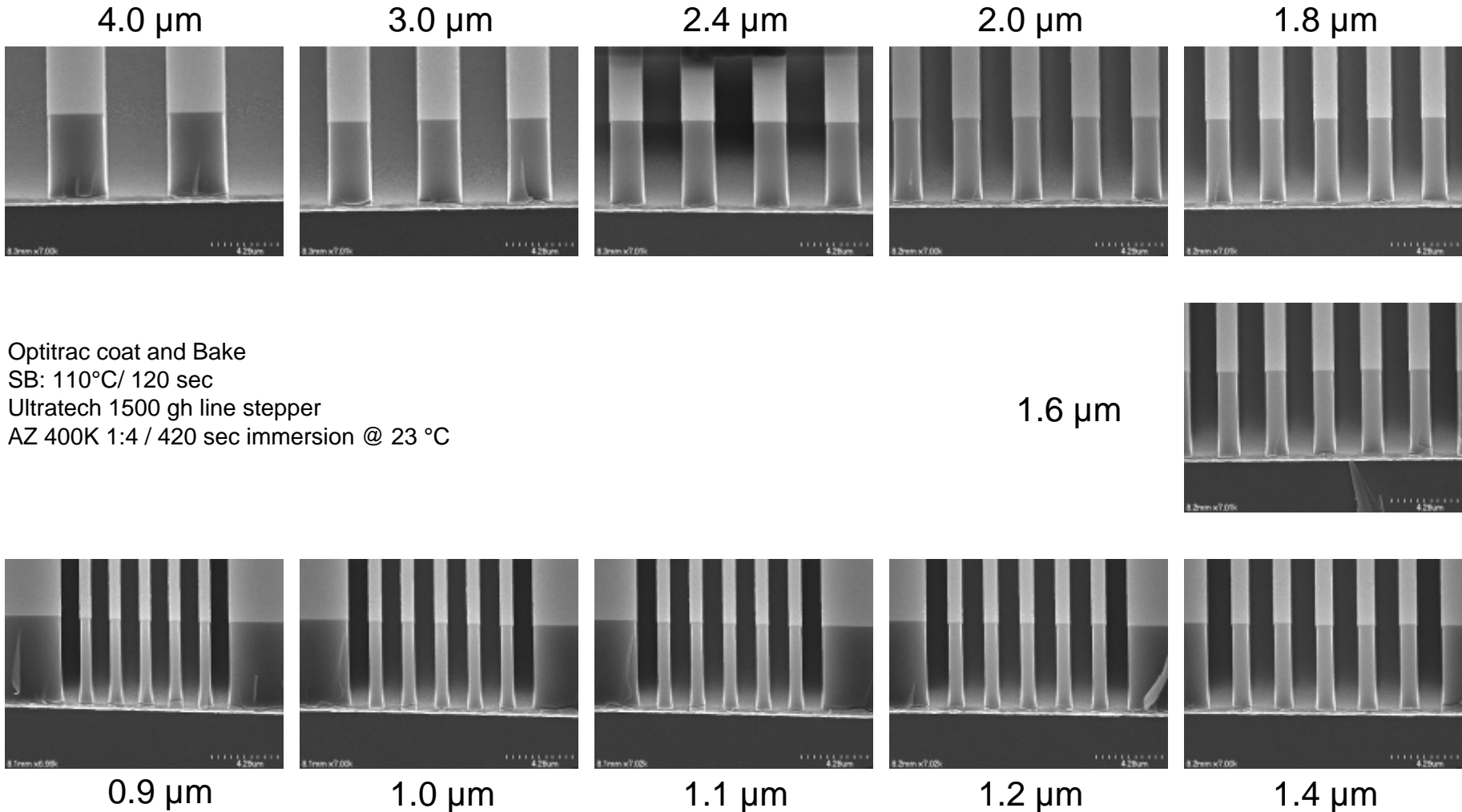
Optitrac coat and Bake
SB: 110°C/ 120 sec
Ultratech 1500 gh line stepper
AZ 400K 1:4 / 420 sec immersion @ 23 °C

800 mJ/cm²

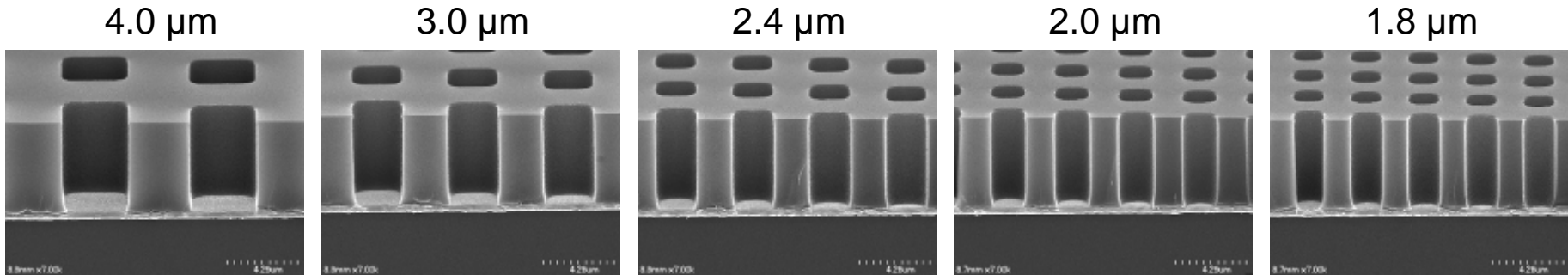


AZ[®] 10XT Photoresist, FT=6 μm

Linearity on Copper @ 850 mJ/cm²

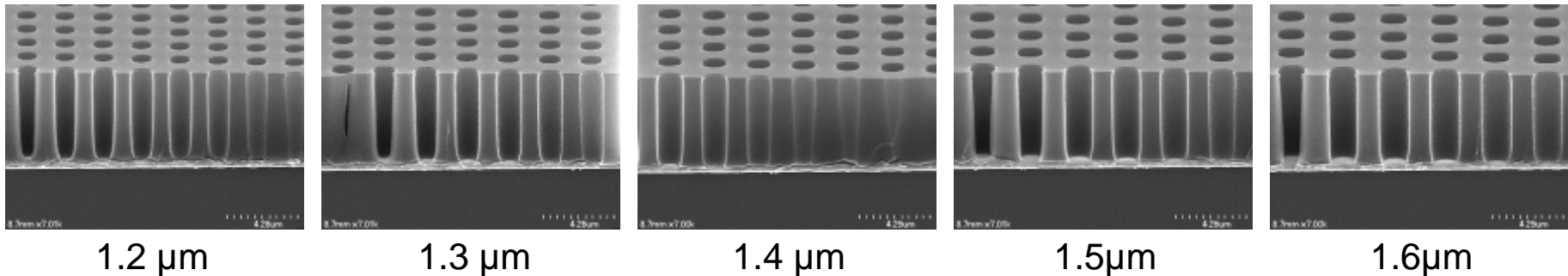
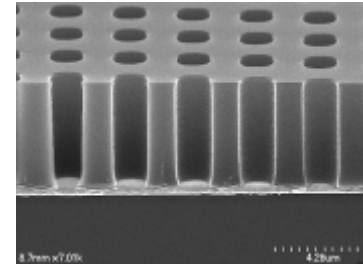


AZ[®] 10XT Photoresist, FT=6 μm CH Linearity on Copper @ 800 mJ/cm²

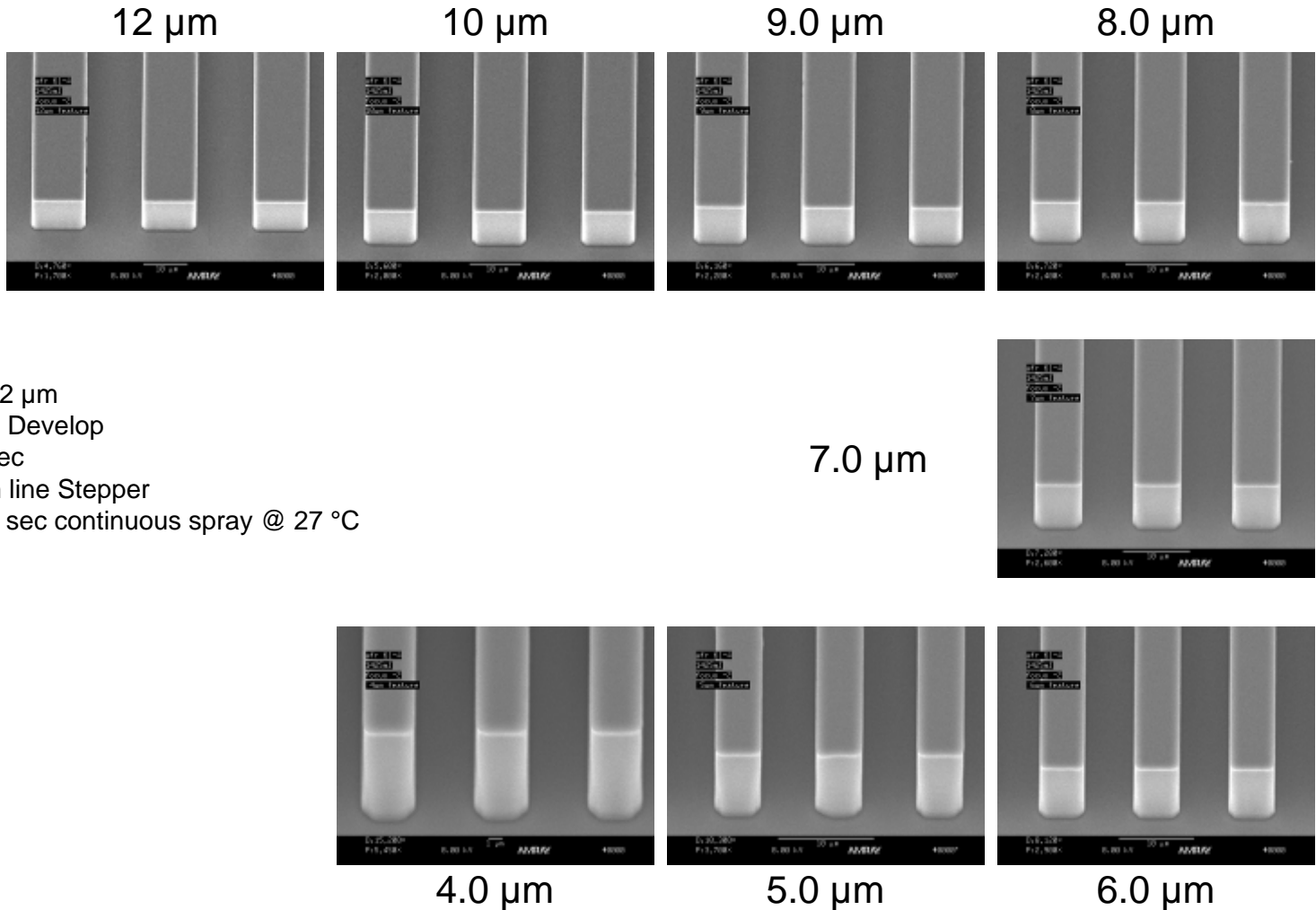


Optitrac coat and Bake
SB: 120°C/ 120 sec
Ultratech 1500 gh line stepper
AZ 400K 1:4 / 420 sec immersion @ 23 °C

1.7 μm



AZ[®] 10XT Photoresist, FT=12 μm Linearity on Silicon @ 1425 mJ/cm^2

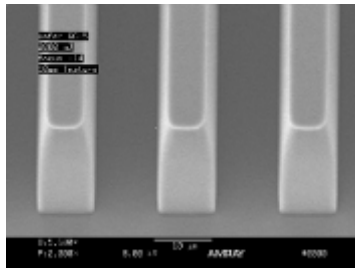


Film Thickness: 12 μm
 Optitrac Coat and Develop
 SB: 110°C/ 180 sec
 Ultratech 1500 gh line Stepper
 AZ 400K 1:4, 260 sec continuous spray @ 27 °C

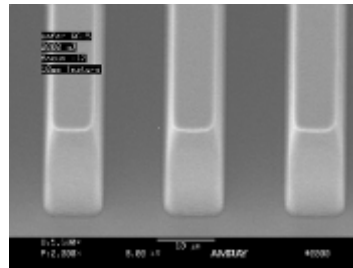
AZ[®] 10XT Photoresist, FT=24 μm

Depth of Focus @ 2000 mJ/cm², 10.0 μm L/S

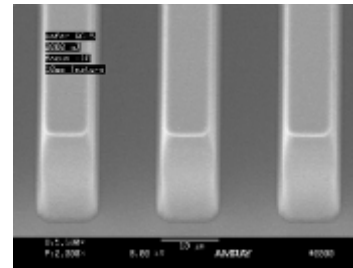
-14.0 μm



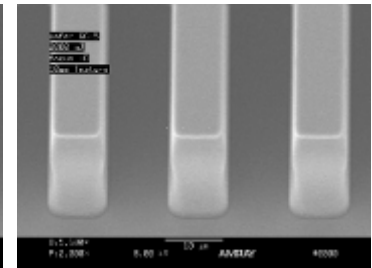
-12.0 μm



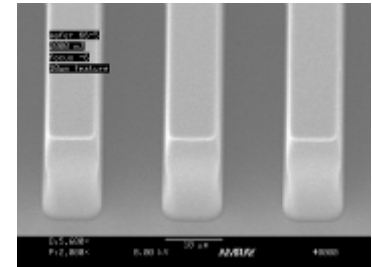
-10.0 μm



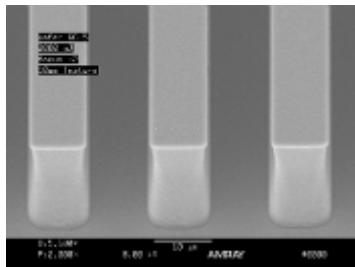
-8.0 μm



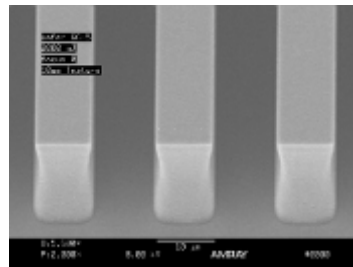
-6.0 μm



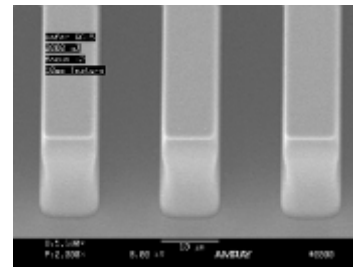
2.0 μm



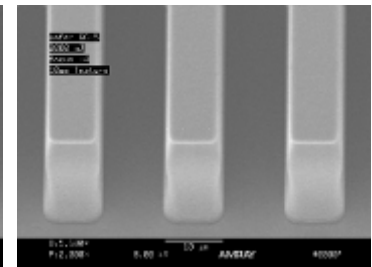
0.0 μm



-2.0 μm



-4.0 μm



Optitrac Coat and Bake
 SB: 1st layer 110°C/ 80 sec
 2nd layer 115°C/180 sec
 Ultratech 1500 gh line Stepper
 AZ 400K 1:4, 600 sec continuous spray @ 27 °C